short title: Customized Equipment Performance Tracking & Analysis

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title:

Equipment Performance Tracking on Equipment-, Lot-, Wafer- and Object-Level – Customized Toolbox to enable detailed analysis and productivity improvements on all Equipment-Types

content:

For adequate Industrial Engineering, detailed analysis of workstations, equipments and wafer histories are needed. Therefore Infineon Dresden started the implementation of an 4-level-toolbox for all Frontend-Equipments. The Performance Tracking Levels are:

- Equipment-View (automated RTC-booking; incl. chambers)
- Lot-View (ProcessSpeed Calculation; SEMI E10 with sub-states; incl. Loading/Unloading)
- Wafer-View (quick Wafer-to-Wafer check)
- Object-View (Wafer-Level and Sub-Equipment-Level; SEMI E90)

For all four levels approach, user benefits and risks will be shown, using examples of Dry-ETC. The major intention is to combine all levels within one Software as a “Zoom-feature”. The presentation addresses major challenges and prerequisites to enable confident data.

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